

SAMCO – RIE PLASMA ASHER

- Switch ON the Gas panel valves O₂, CH₄, PN₂
- Switch ON the Mains & Rotary pump
- Press the ON button of the system, which is given in the front side of the tool
- Reduce the time to 3 secs using +/- buttons near the time display. Press the START button to evacuate and vent the chamber
- Wait for some time to open the chamber & then load the sample
- Press the GV1 and/or GV2 buttons (GV1 for CF₄, GV2 for O₂) as per requirement on the front side of the tool.
- Set the parameters - Time, RF power, gas flow
- RF power ratio for the process is 1:5 i.e., 500 setting units on the panel will generate 100W plasma
- Start the process pressing the START button
- Check the vacuum gauge for the pressure, the desire vacuum around 10⁻¹ Pascal
- Once the system reaches GV point set the gas flow with the given knob of FM1 (CF₄) & FM2 (O₂), Maximum Gas flow range is 50 sccm, for CF₄ & O₂ gases. As per the process recipe set the gas flow.
- After gas flow adjustment Plasma will be generated. Once plasma is generated adjust the plasma range 100 W with the help of Phase & Load Knob (101W will be fine)
- When the given process is over, chamber vents automatically. LED near LV will glow and the system will beep,
- Press the reset button & remove the sample
- Keep the chamber under vacuum after the process is done by pressing START.
- Press the OFF button on the panel after 5 secs.
- Switch OFF the rotary & mains
- Close the gas panel valves